ABSTRACT OF THE DISCLOSURE

METHODS OF FABRICATING INTERFEROMETRIC MODULATORS BY SELECTIVELY REMOVING A MATERIAL

Methods for making MEMS devices such as interferometric modulators involve selectively removing a sacrificial portion of a material to form an internal cavity, leaving behind a remaining portion of the material to form a post structure. The material may be blanket deposited and selectively altered to define sacrificial portions that are selectively removable relative to the remaining portions. Alternatively, a material layer can be laterally recessed away from openings in a covering layer. These methods may be used to make unreleased and released interferometric modulators.

Figure 14